

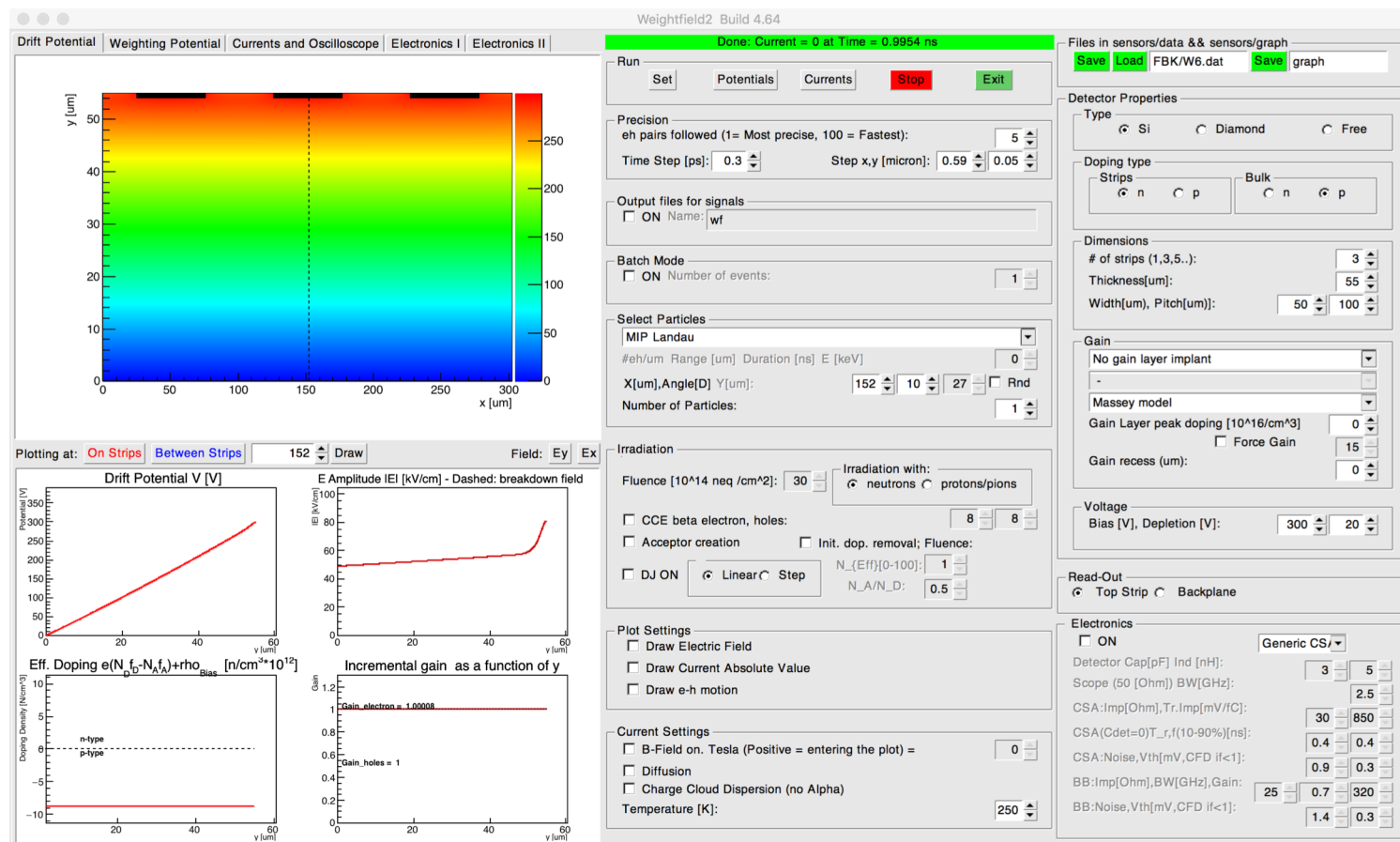
# Weightfield2

Available at:

<http://personalpages.to.infn.it/~cartigli/Weightfield2/Main.html>

It requires Root build from source, it is for Linux and Mac.

It will not replace TCAD, but it helps in understanding the sensors response

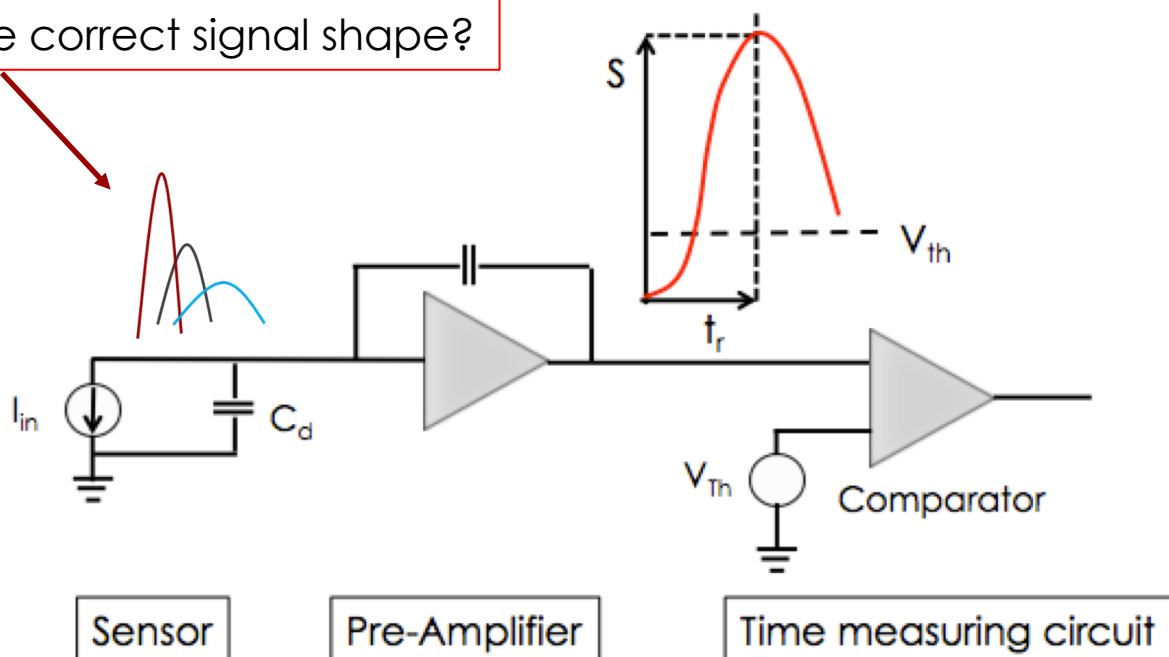


# Why did we design WF2?

From Angelo's keynote talk:

- Electronics for ps timing is (in principle) already there!
- **But what about sensors?**
- Sensor and front-end codesign essential to achieve best possible timing

What is the correct signal shape?



# Weightfield2

---

Highlights:

- It is completely open source
- it's fast
- It generates the signal from several sources (MIP, alpha, lasers..)
- Runs in batch mode writing output files
- It loads/save configurations
- It has basics electronics simulation

**It crashes occasionally**

How to use it:

Obtain the last version from

<http://personalpages.to.infn.it/~cartigli/Weightfield2/Main.html>

- 1) From the download page, get the latest version
- 2) Unzip it and then type:
- 3) Make or 3-bis) make -f Makefile\_MacOS10.10\_root6
- 4) ./weightfield

# WF2 layout

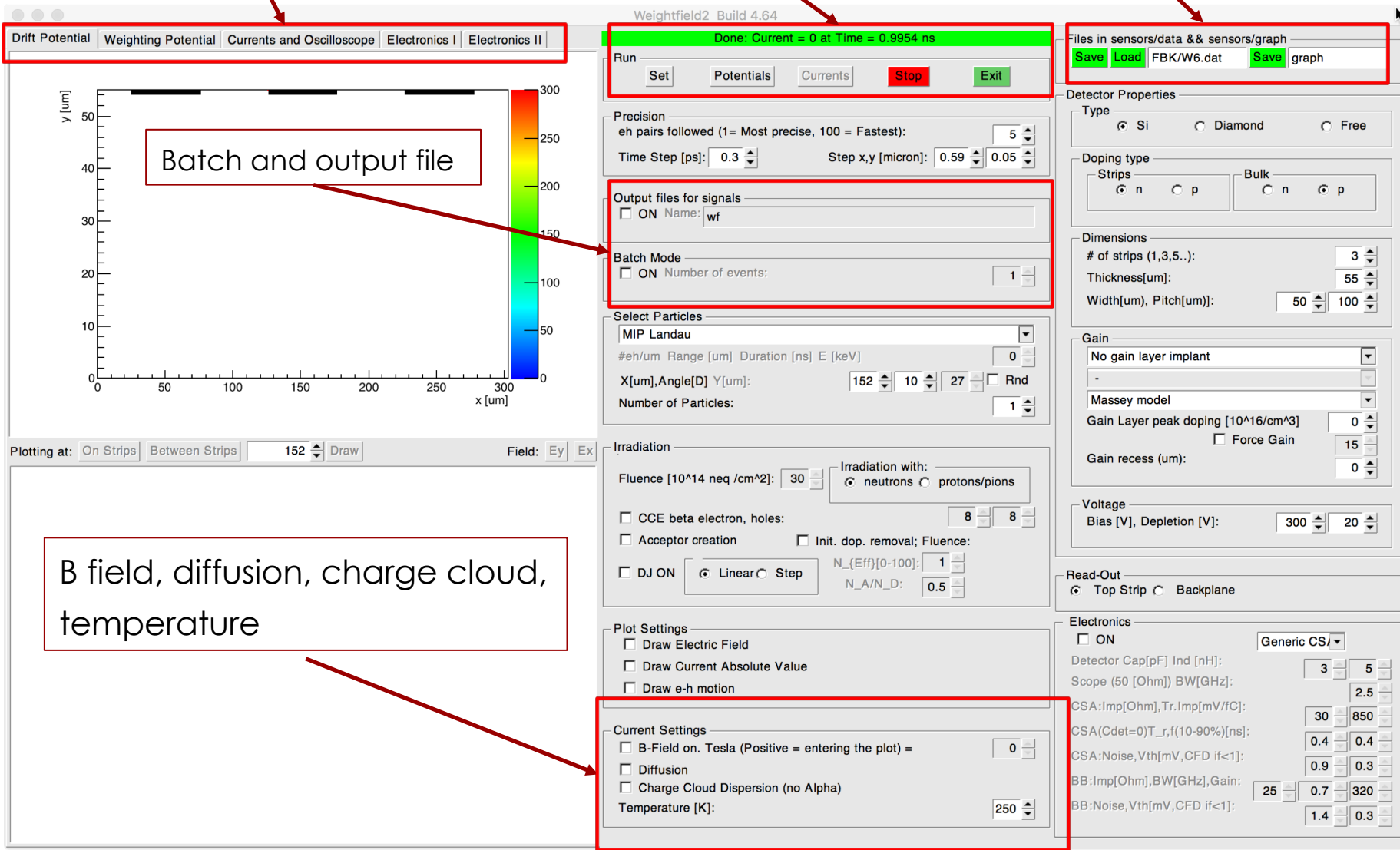
4 tabs: field, Weighting field, currents, and electronics

Controls

The program can save/load your configuration and the plots

Batch and output file

B field, diffusion, charge cloud, temperature





# Step 1: select your sensor

Weightfield2 Build 4.64

Done: Current = 0 at Time = 0.9954 ns

Run: Set Potentials Currents Stop Exit

Precision  
eh pairs followed (1= Most precise, 100 = Fastest): 5  
Time Step [ps]: 0.3 Step x,y [micron]: 0.59 0.05

Output files for signals  
☐ ON Name: wf

Batch Mode  
☐ ON Number of events: 1

Select Particles  
MIP Landau  
#eh/um Range [um] Duration [ns] E [keV] 0  
X[um],Angle[D] Y[um]: 152 10 27 ☐ Rnd  
Number of Particles: 1

Irradiation  
Fluence [10<sup>14</sup> neq /cm<sup>2</sup>]: 30  
Irradiation with: ☒ neutrons ☐ protons/pions  
☐ CCE beta electron, holes: 8 8  
☐ Acceptor creation ☐ Init. dop. removal; Fluence:  
☐ DJ ON ☒ Linear ☐ Step N<sub>{Eff}</sub>[0-100]: 1  
N<sub>A</sub>/N<sub>D</sub>: 0.5

Plot Settings  
☐ Draw Electric Field  
☐ Draw Current Absolute Value  
☐ Draw e-h motion

Current Settings  
☐ B-Field on. Tesla (Positive = entering the plot) = 0  
☐ Diffusion  
☐ Charge Cloud Dispersion (no Alpha)  
Temperature [K]: 250

Files in sensors/data && sensors/graph  
Save Load FBK/W6.dat Save graph

Detector Properties  
Type: ☒ Si ☐ Diamond ☐ Free  
Doping type: Strips ☒ n ☐ p Bulk ☐ n ☒ p  
Dimensions  
# of strips (1,3,5..): 3  
Thickness[um]: 55  
Width[um], Pitch[um]: 50 100  
Gain  
No gain layer implant  
Massey model  
Gain Layer peak doping [10<sup>16</sup>/cm<sup>3</sup>]: 0  
☐ Force Gain 15  
Gain recess (um): 0  
Voltage  
Bias [V], Depletion [V]: 300 20

Read-Out  
☒ Top Strip ☐ Backplane

Electronics  
☐ ON Generic CS  
Detector Cap[pF] Ind [nH]: 3 5  
Scope (50 [Ohm]) BW[GHz]: 2.5  
CSA:Imp[Ohm],Tr.Imp[mV/fC]: 30 850  
CSA(Cdet=0)T<sub>r</sub>,f(10-90%)[ns]: 0.4 0.4  
CSA:Noise,Vth[mV,CFD if<1]: 0.9 0.3  
BB:Imp[Ohm],BW[GHz],Gain: 25 0.7 320  
BB:Noise,Vth[mV,CFD if<1]: 1.4 0.3

Drift Potential Weighting Potential Currents and Oscilloscope Electronics I Electronics II

Plotting at: On Strips Between Strips 152 Draw Field: Ey Ex

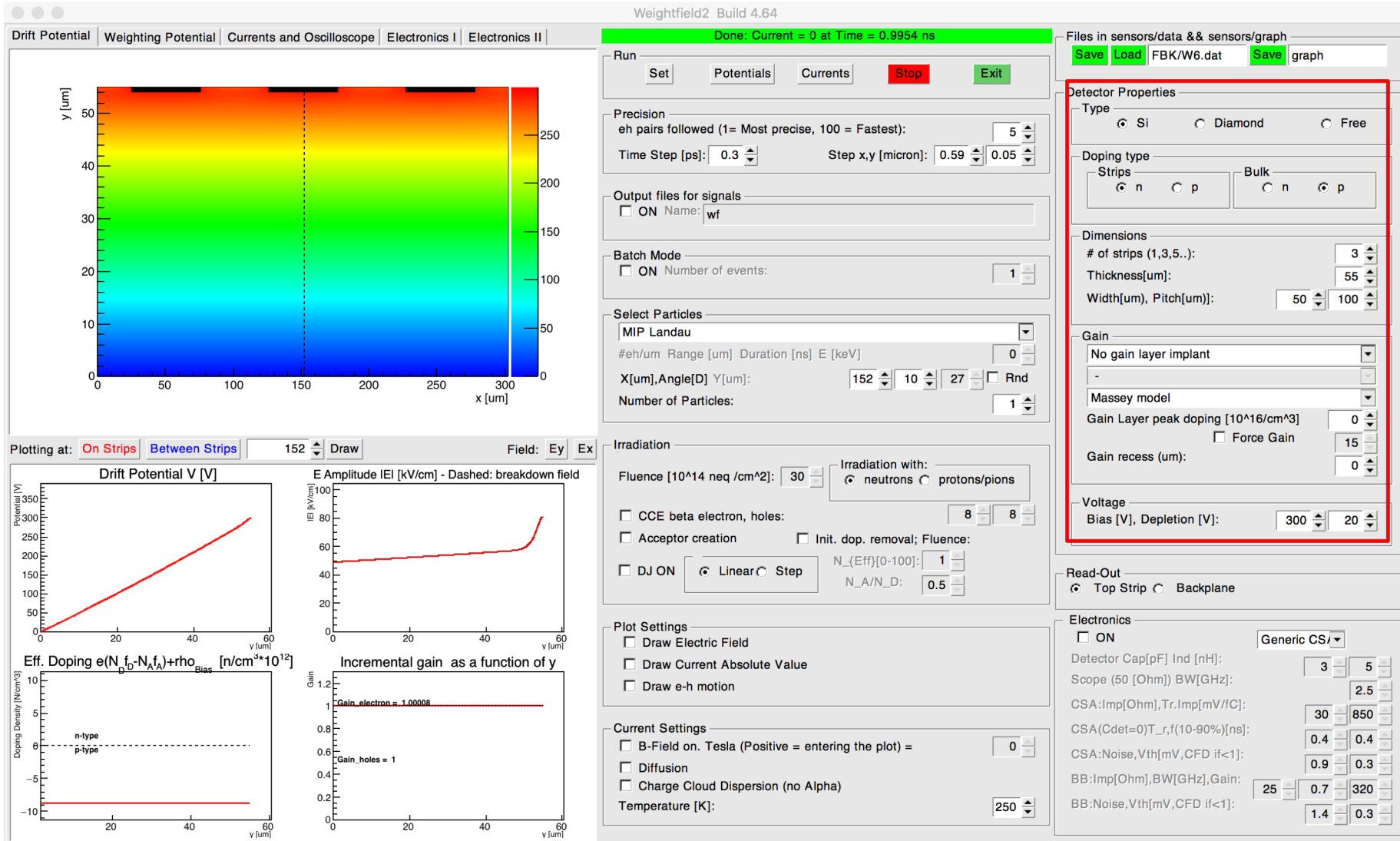
y [um] 50 40 30 20 10 0  
x [um] 0 50 100 150 200 250 300

Color scale: 300 250 200 150 100 50 0

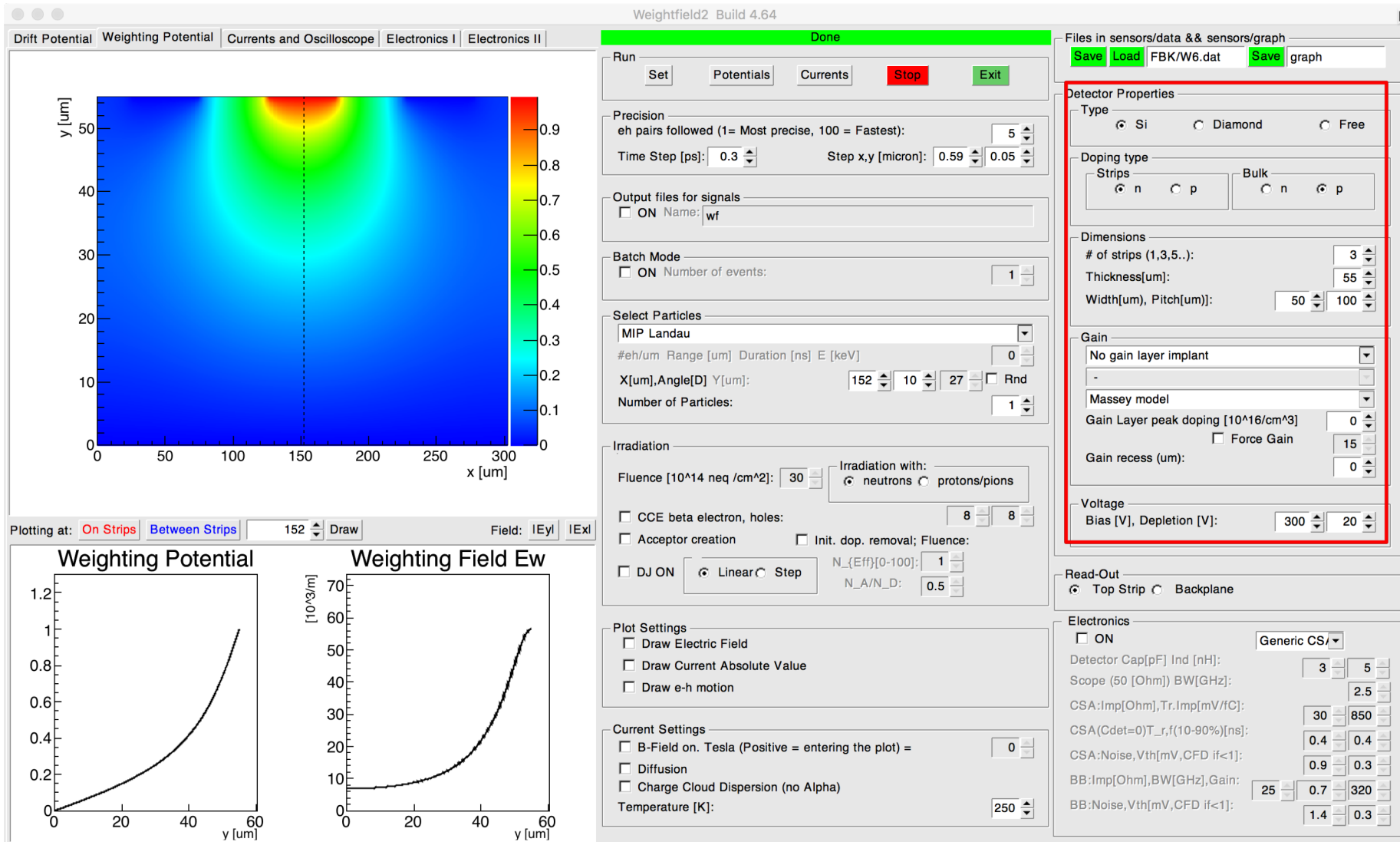
# Fields: under the hood

- The program loads your geometry
- Compute the silicon resistivity from the depletion voltage
- It uses an iterative method to compute:
  - The electric field
  - The weighting field

# Step 1: E field

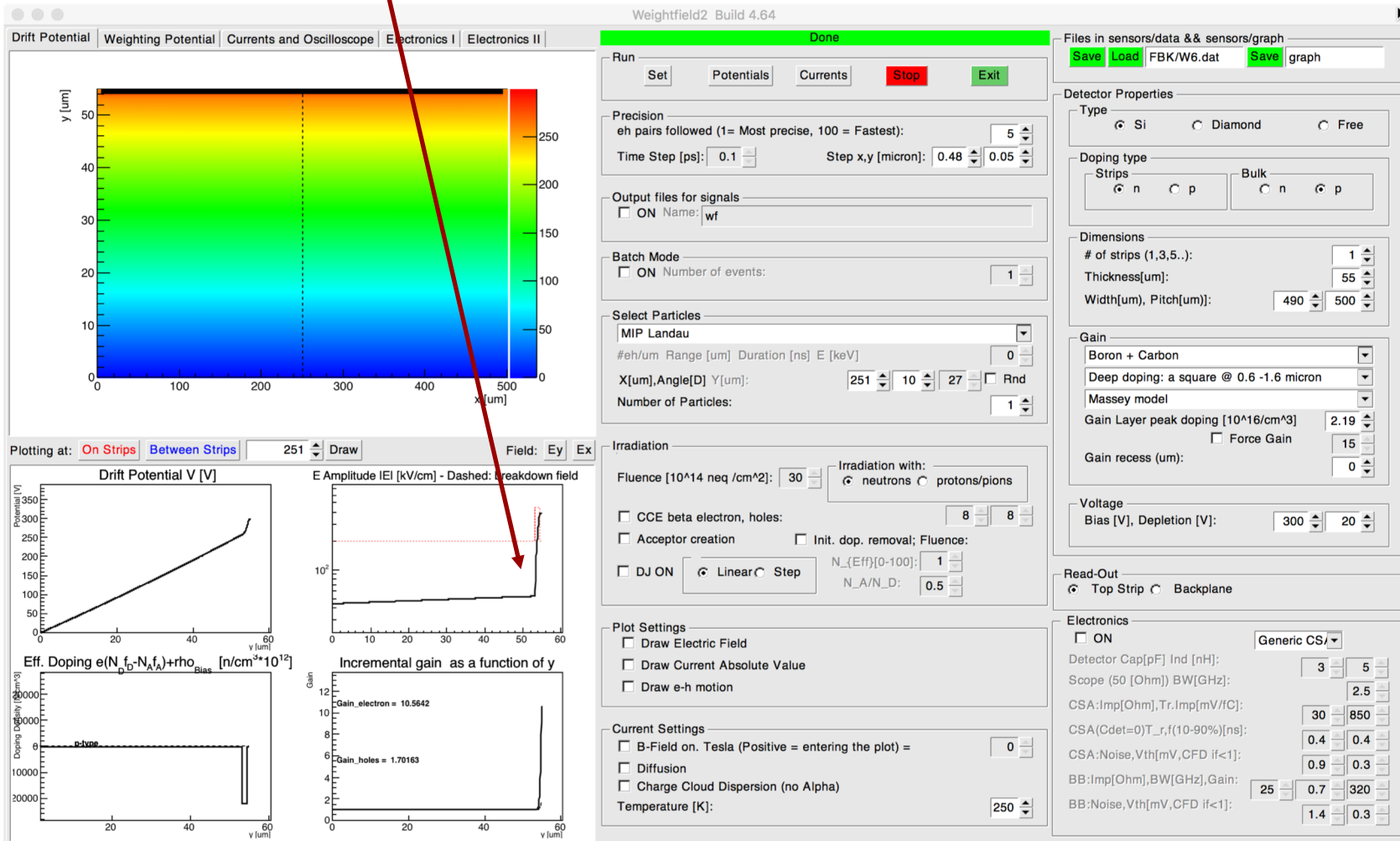


# Step 1: W field



# Select your sensor: does it have gain?

- The program implements a gain layer
- It computes the contribution from the additional doping to the electric field

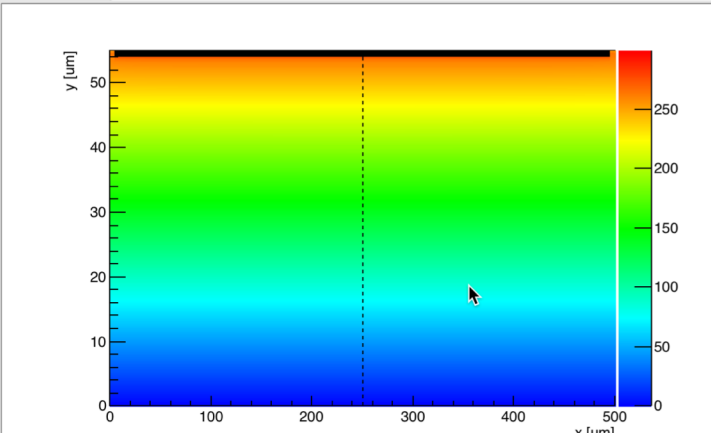


# Step 2: select the particle

Grab File Edit Capture Window Help

Weightfield2 Build 4.64

Drift Potential Weighting Potential Currents and Oscilloscope Electronics I Electronics II



Done

Run Set Potentials Currents Stop Exit

Precision  
eh pairs followed (1= Most precise, 100 = Fastest): 5

Time Step [ps]: 0.1 Step x,y [micron]: 0.48 0.05

Output files for signals  
☐ ON Name: wf

Batch Mode  
☐ ON Number of events: 1

Select Particles

- MIP Landau
- MIP: uniform Q, Qtot =  $q \cdot [\#eh/um] \cdot Height$
- MIP: NON uniform Q, Qtot =  $q \cdot [\#eh/um] \cdot Height$
- MIP Landau
- Laser (1064 nm): Top-TCT, Q =  $q \cdot [\#eh/um] \cdot Height$
- Laser (1064 nm): Edge-TCT, Q =  $q \cdot [\#eh/um] \cdot Height$
- Edge MIP Landau

Irradiation

Fluence [ $10^{14}$  neq /cm<sup>2</sup>]: 30 Irradiation with: ☒ neutrons ☐ protons/pions

☐ CCE beta electron, holes: 8 8

☐ Acceptor creation ☐ Init. dop. removal; Fluence:

☐ DJ ON ☒ Linear ☐ Step

$N_{eff}[0-100]: 1$

$N_A/N_D: 0.5$

Plot Settings

☐ Draw Electric Field

☐ Draw Current Absolute Value

☐ Draw e-h motion

Current Settings

☐ B-Field on. Tesla (Positive = entering the plot) = 0

☐ Diffusion

☐ Charge Cloud Dispersion (no Alpha)

Temperature [K]: 250

Files in sensors/data && sensors/graph

Save Load FBK/W6.dat Save graph

Detector Properties

Type ☒ Si ☐ Diamond ☐ Free

Doping type

Strips ☒ n ☐ p Bulk ☐ n ☒ p

Dimensions

# of strips (1,3,5..): 1

Thickness[um]: 55

Width[um], Pitch[um]: 490 500

Gain

Boron + Carbon

Deep doping: a square @ 0.6 -1.6 micron

Massey model

Gain Layer peak doping [ $10^{16}/cm^3$ ]: 2.19

☐ Force Gain 15

Gain recess (um): 0

Voltage

Bias [V], Depletion [V]: 300 20

Read-Out

☒ Top Strip ☐ Backplane

Electronics

☐ ON Generic CS

Detector Cap[pF] Ind [nH]: 3 5

Scope (50 [Ohm]) BW[GHz]: 2.5

CSA:Imp[Ohm], Tr.Imp[mV/IC]: 30 850

CSA(Cdet=0)T\_r,f(10-90%)[ns]: 0.4 0.4

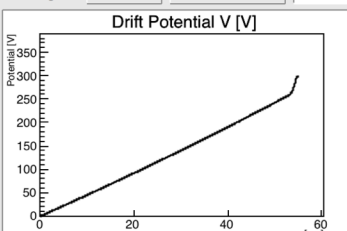
CSA:Noise,Vth[mV,CFD if<1]: 0.9 0.3

BB:Imp[Ohm], BW[GHz], Gain: 25 0.7 320

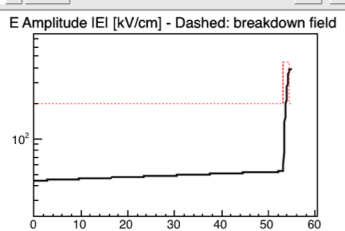
BB:Noise,Vth[mV,CFD if<1]: 1.4 0.3

Plotting at: On Strips Between Strips 251 Draw Field: Ey Ex

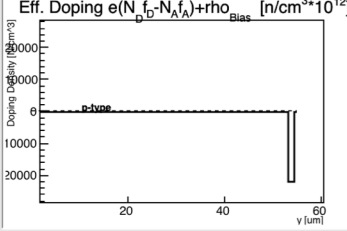
Drift Potential V [V]



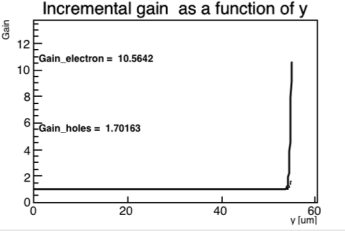
E Amplitude |E| [kV/cm] - Dashed: breakdown field



Eff. Doping  $e(N_D - N_A) + \rho$  [n/cm<sup>3</sup> \* 10<sup>12</sup>]

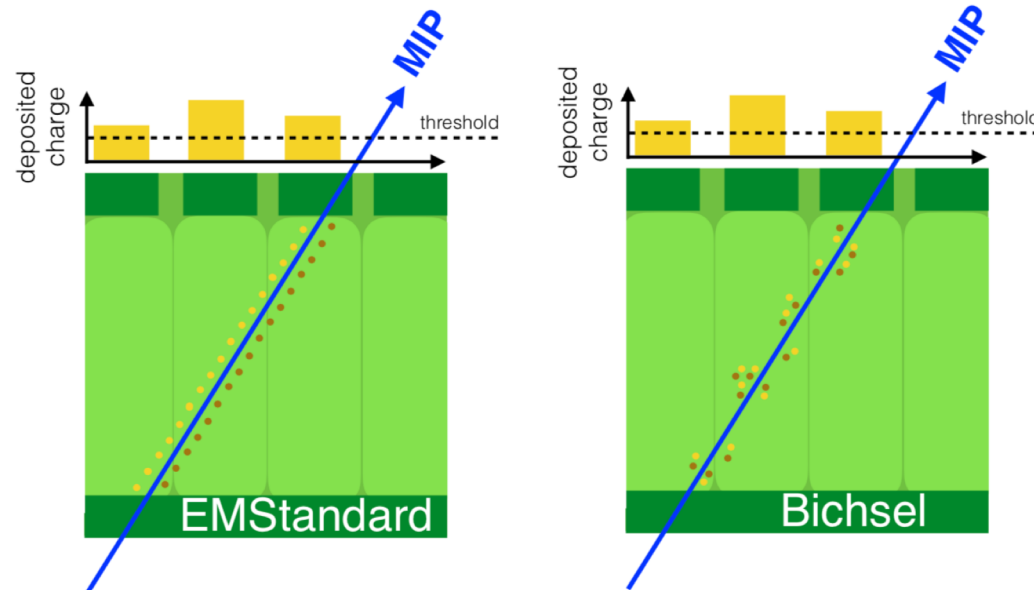


Incremental gain as a function of v



# Landau: under the hood

The program uses GEANT4 with the photo-absorption ionization (PAI) model to generate non uniform charge depositions



Results cross-checked with several publications, for example:

## **The Impact of Incorporating Shell-corrections to Energy Loss in Silicon**

Fuyue Wang, Dong Su, Benjamin Nachman, Maurice Garcia-Sciveres, and Qi Zeng  
arXiv:1711.05465v2 [physics.ins-det]

“ The ionization energy loss fluctuation in very thin silicon sensors significantly deviates from the Landau distribution. Therefore, we have developed a charge deposition setup that implements the Bichsel straggling function, which accounts for shell-effects. “

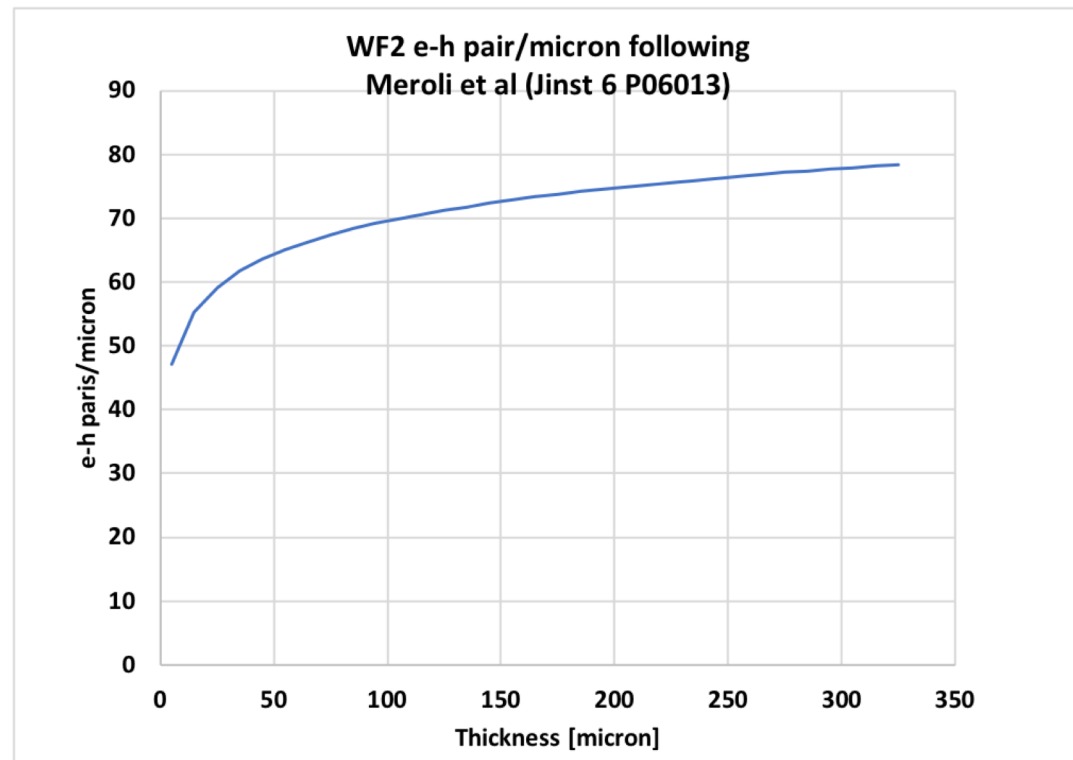
# Landau: under the hood

## Landau distribution

$$\text{MPV} = d * [0.027 * \ln(d) + 0.126]$$

$$\text{FWHM} = 0.31 * d^{0.81}$$

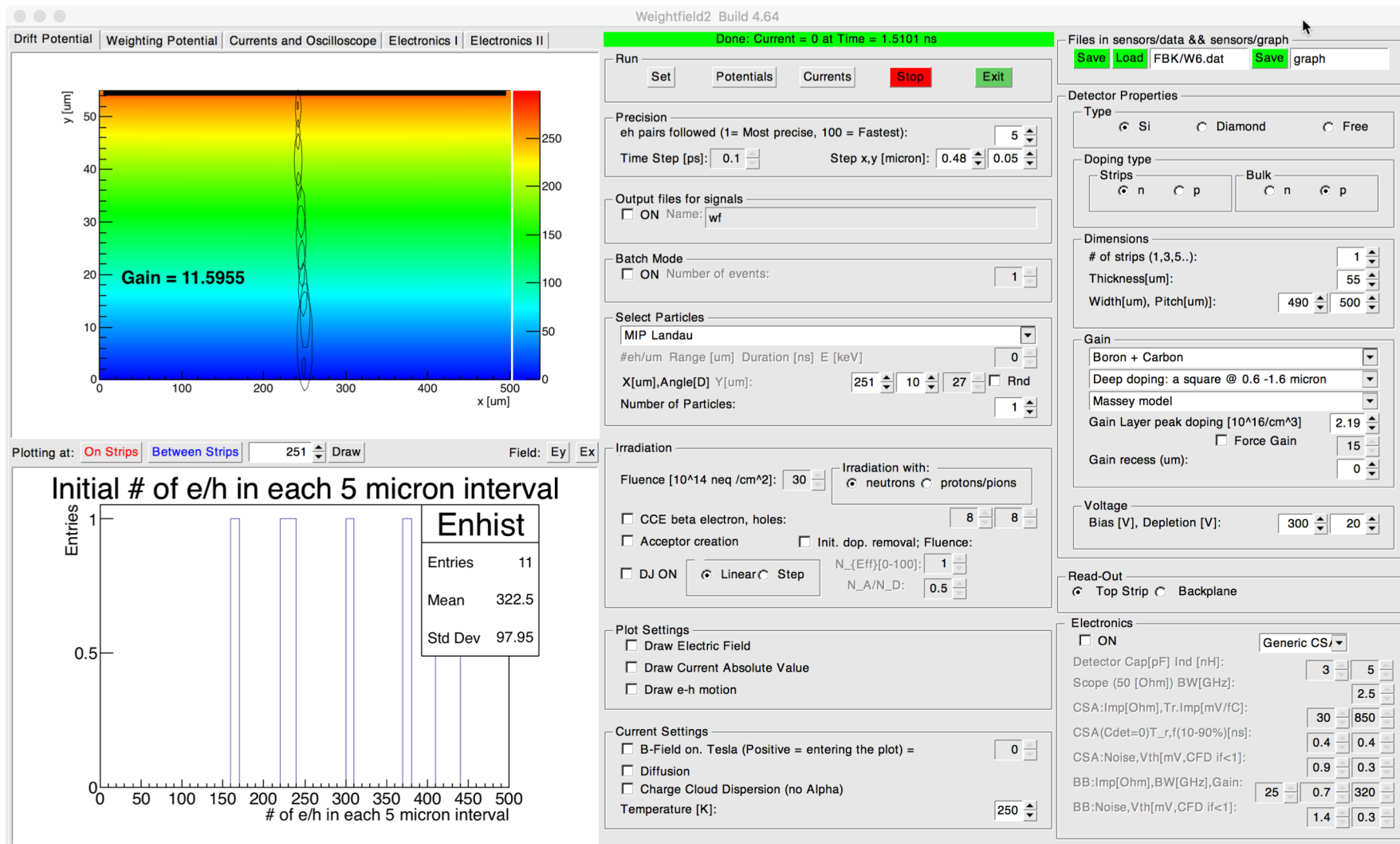
$$\frac{\text{FWHM}}{\text{MPV}} = 2.1 * d^{-0.3}$$



Following Meroli et al (Jinst 6 P06013), these are the parameterizations of the MPV and FWHM as a function of the sensor thickness  $d$  for the Landau distribution in silicon



# Step 3: charge carriers drift



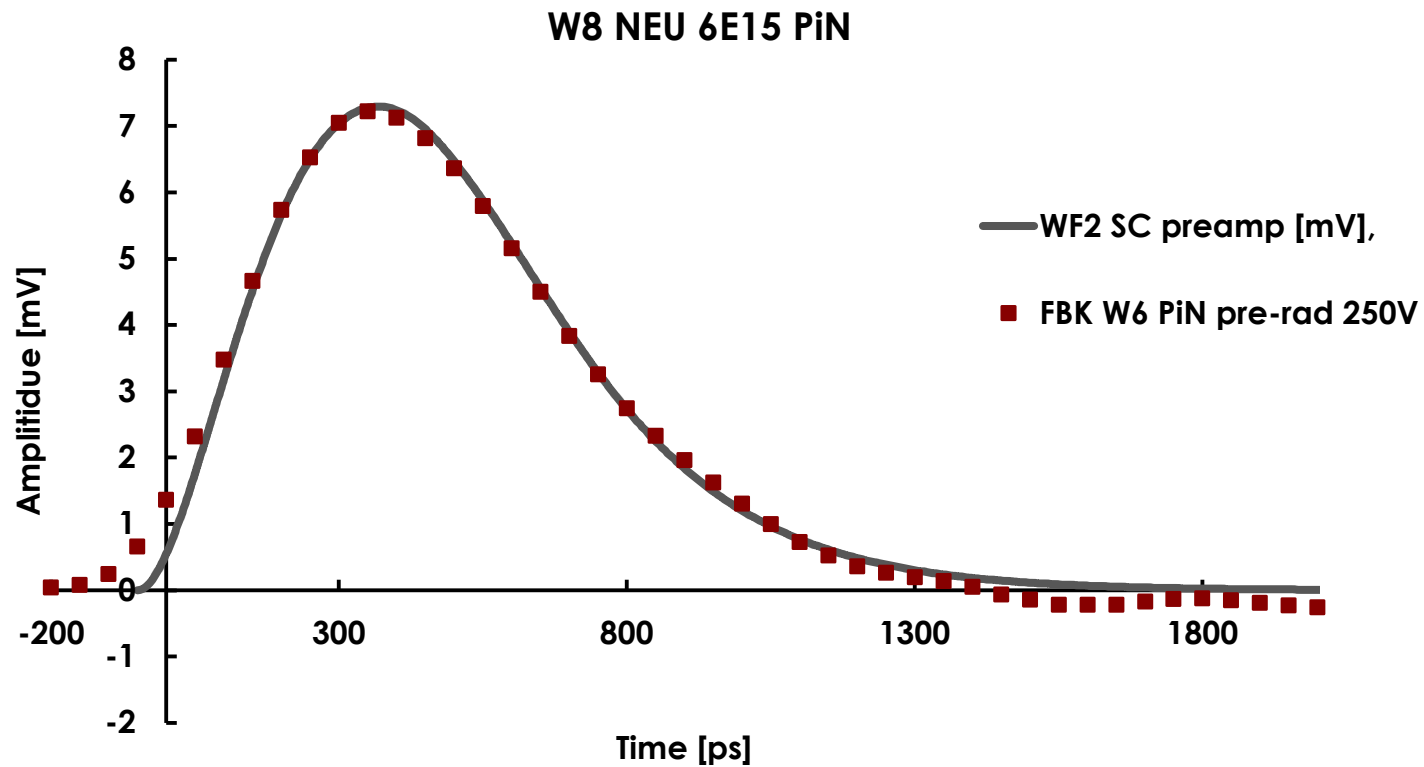
# drift: under the hood

Current is generated using Ramo's theorem:  $i(t) = qv(t)E_w$

$$I_{tot}(t_j) = \sum_{k=1}^n I_k(t_j) = -q \sum_{k=1}^n \overrightarrow{v_k(t_j, x_k)} \cdot \overrightarrow{E_w}(x_k)$$

	Electrons	Holes
$\mu(T) \text{ [m}^2/\text{Vs}]$	$0.1414 \left(\frac{T}{300K}\right)^{-2.5}$	$0.0470 \left(\frac{T}{300K}\right)^{-2.2}$
$\beta(T)$	$1.09 \left(\frac{T}{300K}\right)^{0.66}$	$1.213 \left(\frac{T}{300K}\right)^{0.17}$
$v_{sat}(T) \text{ [m/s]}$	$1.07e5 \left(\frac{300K}{T}\right)^{0.87}$	$8.35e4 \left(\frac{300K}{T}\right)^{0.52}$
$v(x, T) \text{ [m/s]}$	$\frac{\mu_e(T)E_d(x)}{\sqrt[1/\beta_e(T)]{1 + \left(\frac{\mu_e(T)E_d(T)}{v_{e,Sat}(T)}\right)^{\beta_e(T)}}}$	$\frac{\mu_h(T)E_d(x)}{\sqrt[1/\beta_h(T)]{1 + \left(\frac{\mu_h(T)E_d(x)}{v_{h,Sat}(T)}\right)^{\beta_h(T)}}}$

# WF2 – Data: current in PiN



# gain: under the hood

If the electric field is high enough, carriers multiply

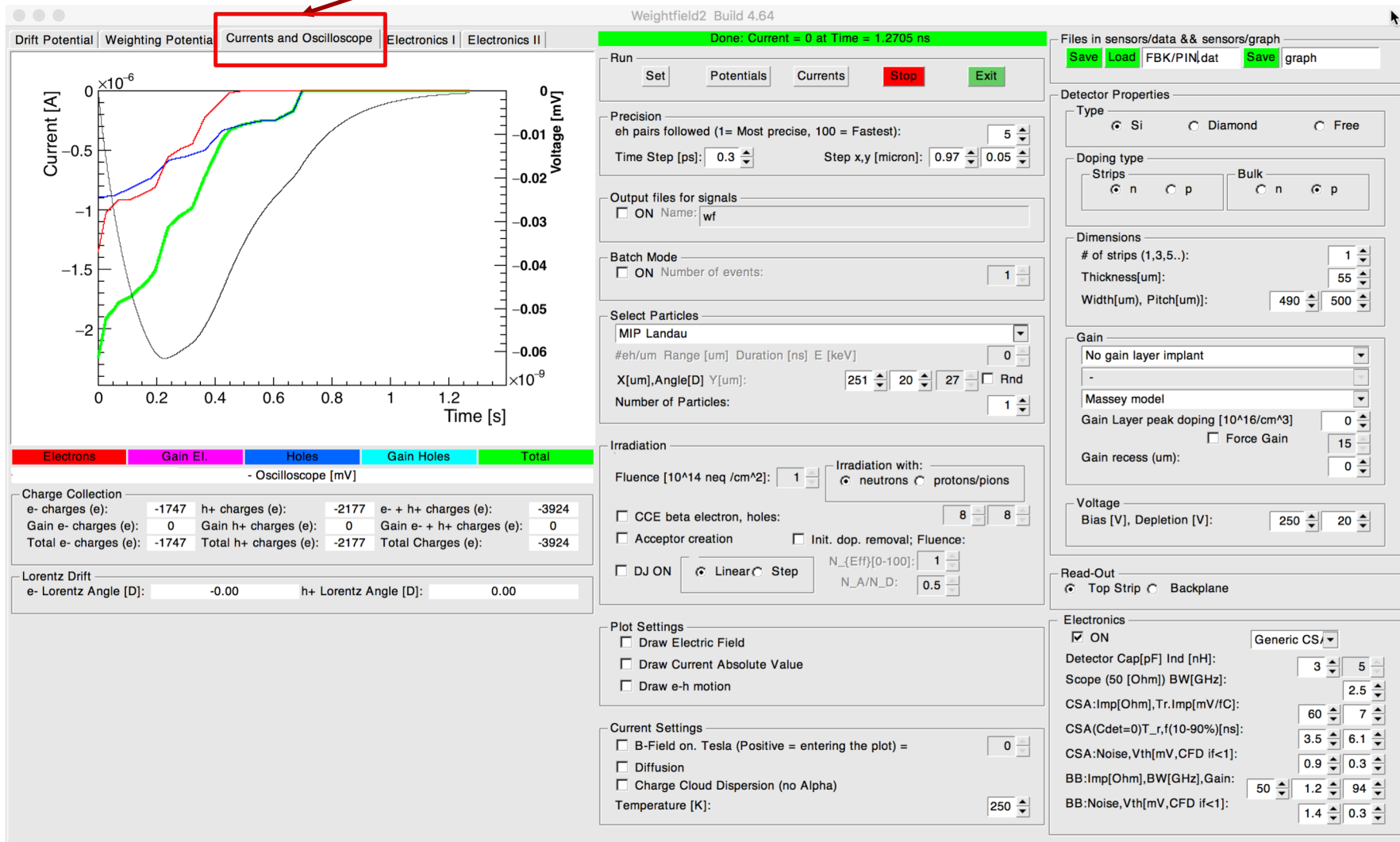
$$N_e(x) = N_e e^{\beta x}; \quad N_h(x) = N_h e^{\alpha x}$$

$$\alpha = A_n \exp\left\{-\frac{B_n}{E}\right\} ;$$
$$\beta = A_p \exp\left\{-\frac{B_p}{E}\right\} ,$$

$$B_{n,p}(T) = C_{n,p} + D_{n,p} T$$

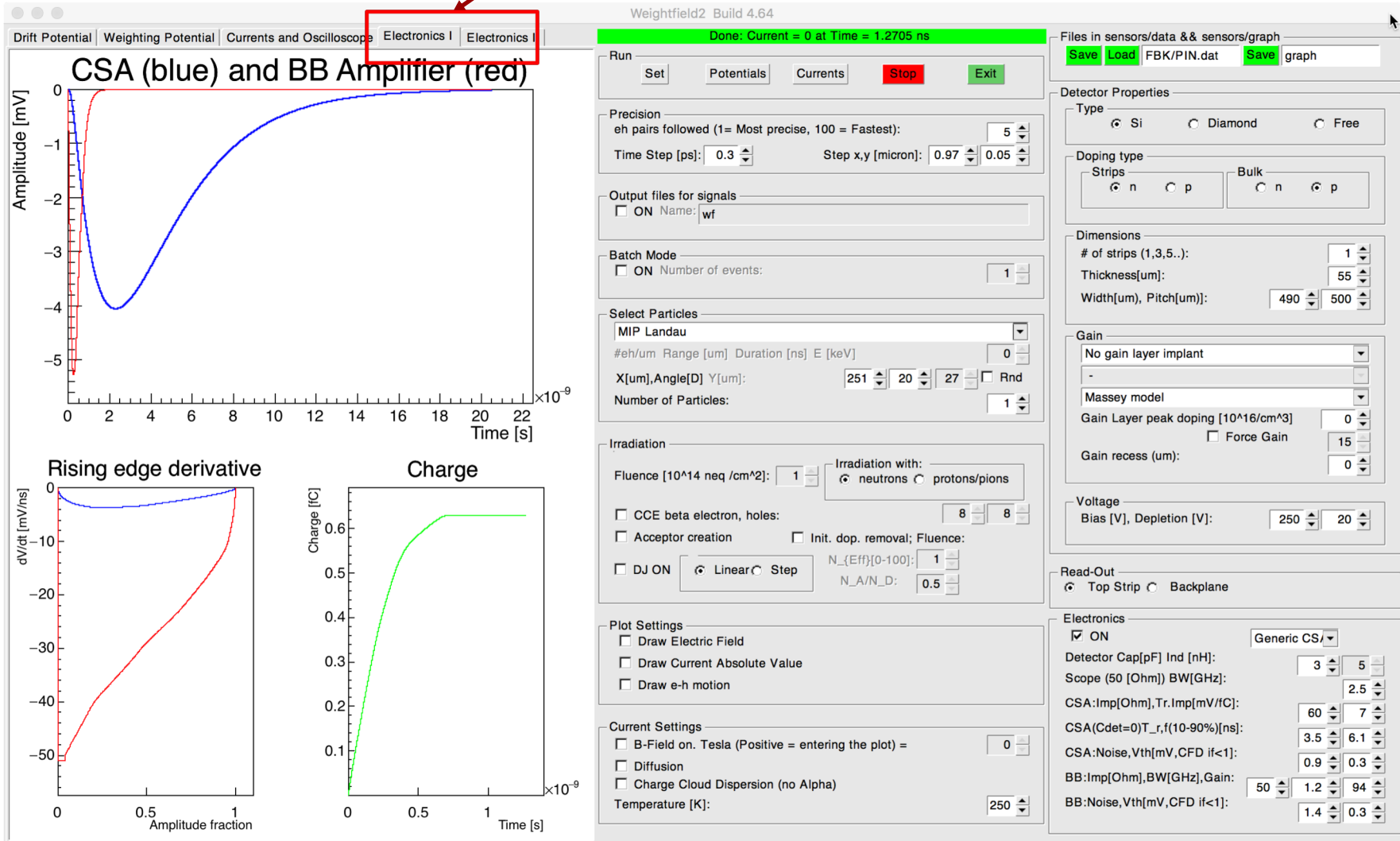
# Currents

Current tabs

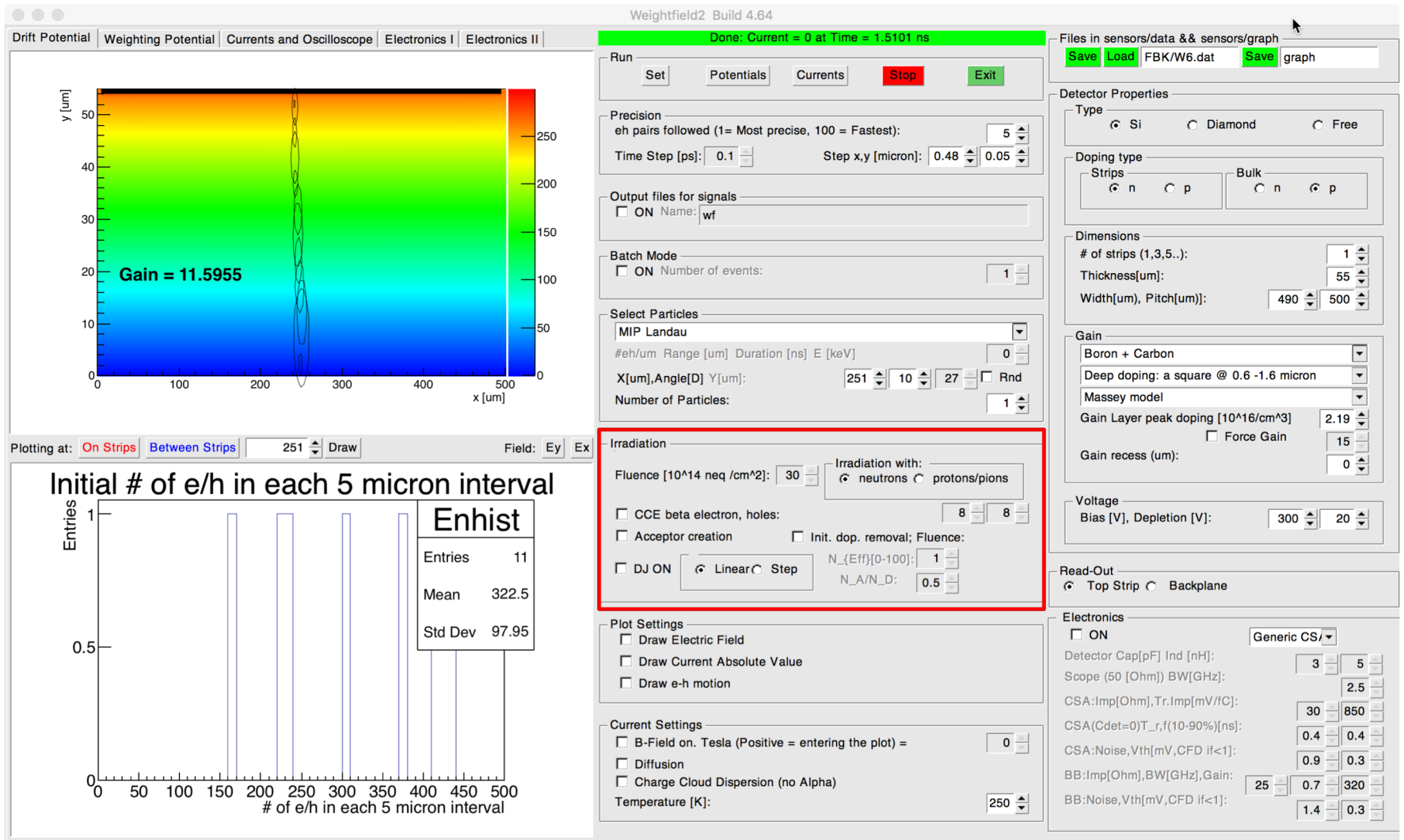


# Electronics

Electronics tabs



# Step 4: radiation damage



# Step 4: under the hood

Charge trapping with fluence  $\phi$ :

$$i(t) = i(t)_{new} e^{-t/\tau}$$

$$\tau = \beta \phi \leftarrow \text{model under discussion}$$

Acceptor removal:

$$N(\phi) = N(0) * e^{-c\phi}$$

Acceptor creation:

$$N(\phi) = \beta \phi$$

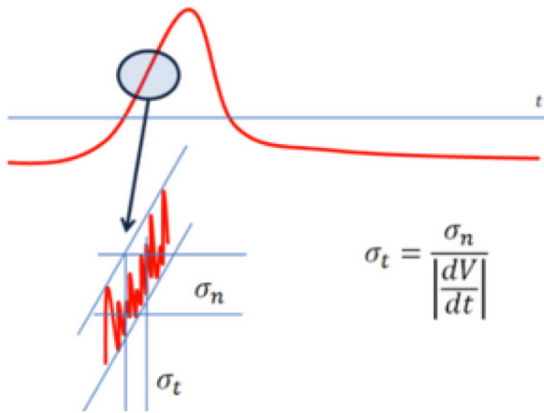


# WF2: predictions

$$\sigma_t = \left( \frac{N}{dV/dt} \right)^2 + (\text{Landau Shape})^2 + \text{TDC}$$

Usual "Jitter" term

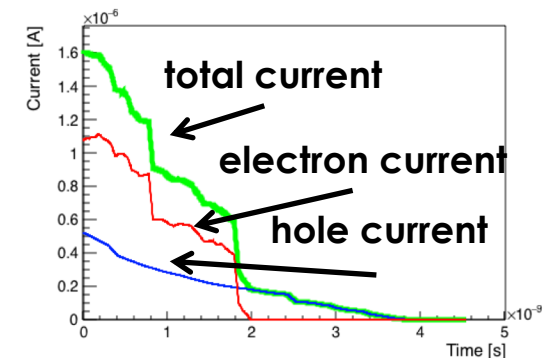
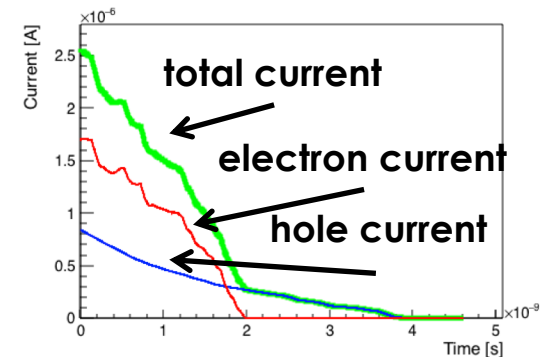
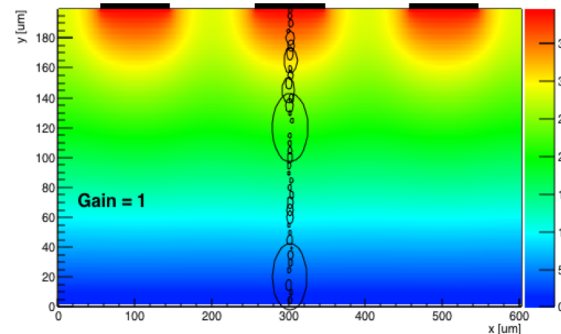
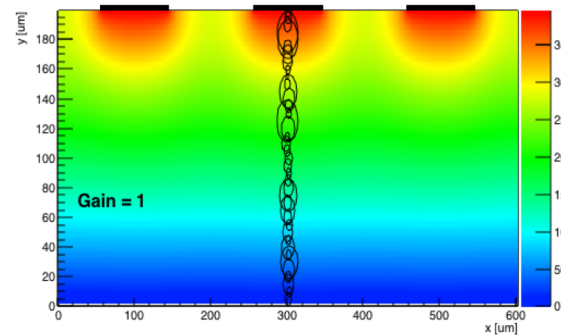
Here enters everything that  
is "Noise" and the  
steepness of the signal



**Need large dV/dt**

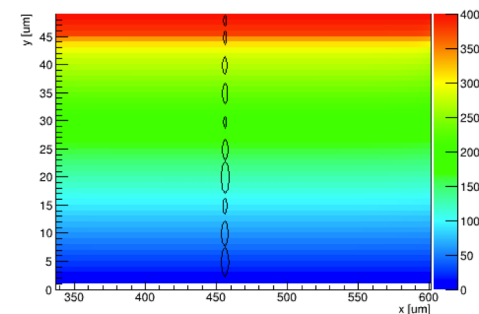
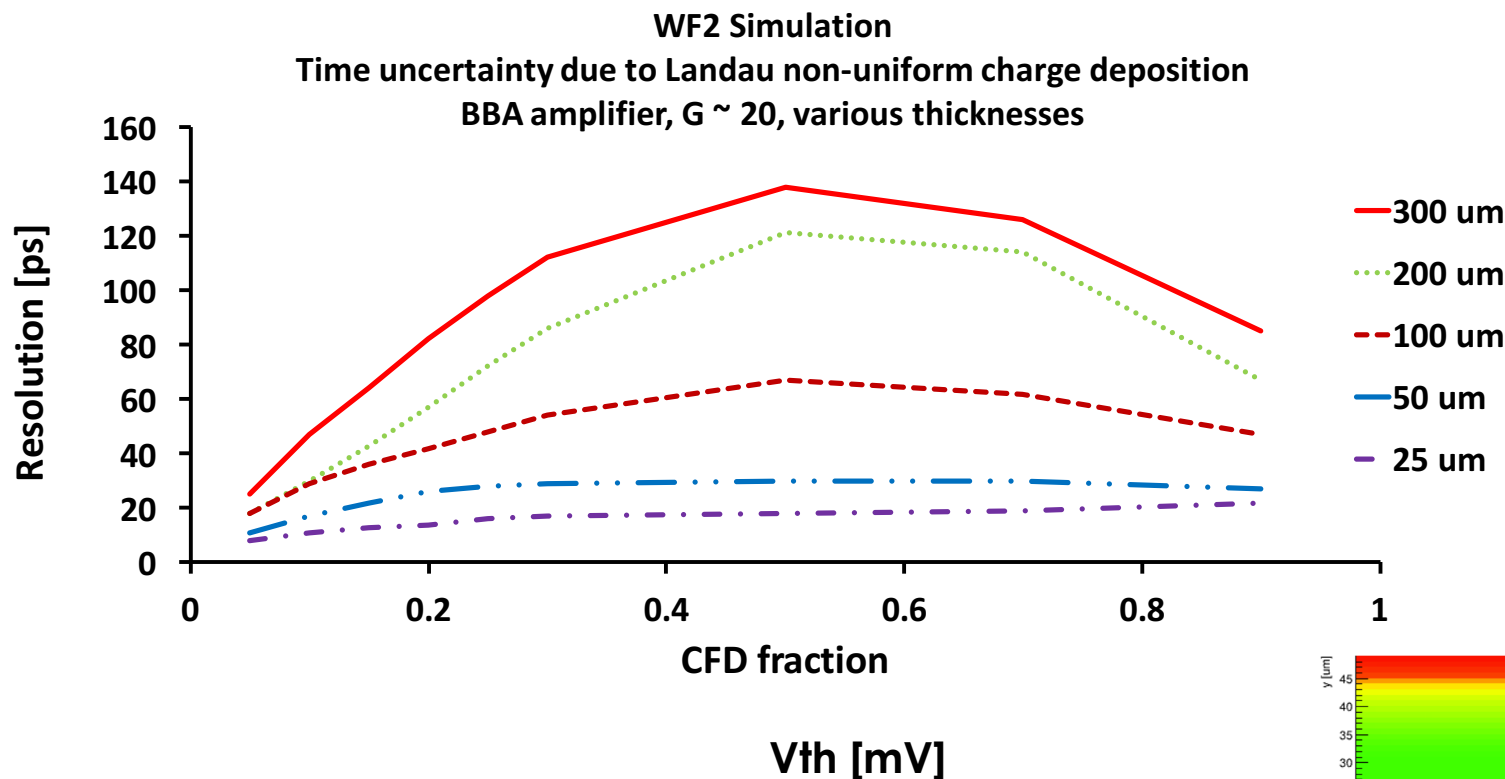
**Time walk:** Amplitude variation, corrected in electronics

**Shape variations:** non homogeneous energy



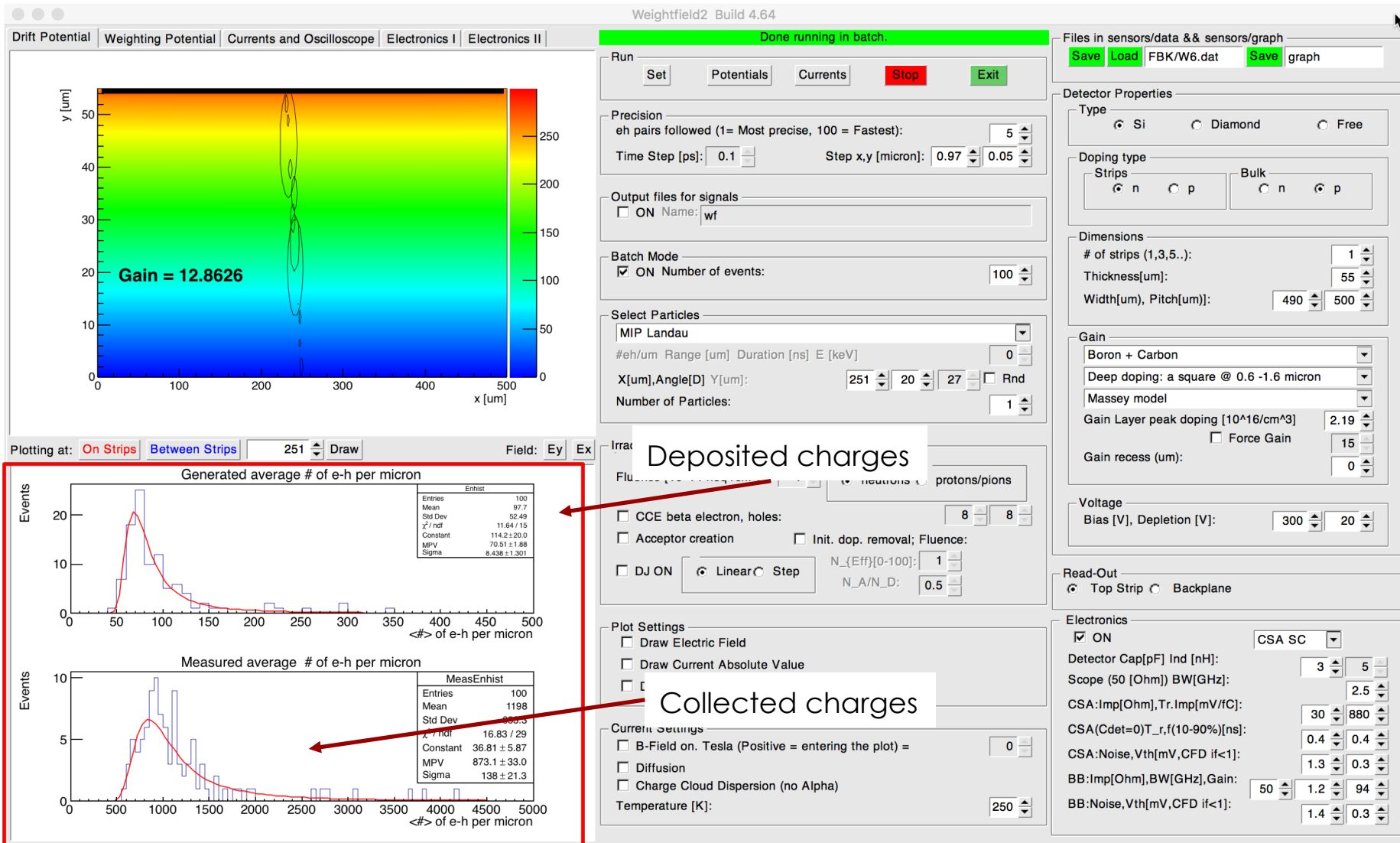
# Non uniform charge deposition along the track

This is a physical limit to time resolution:  
Need to use thin detectors and low comparator threshold.

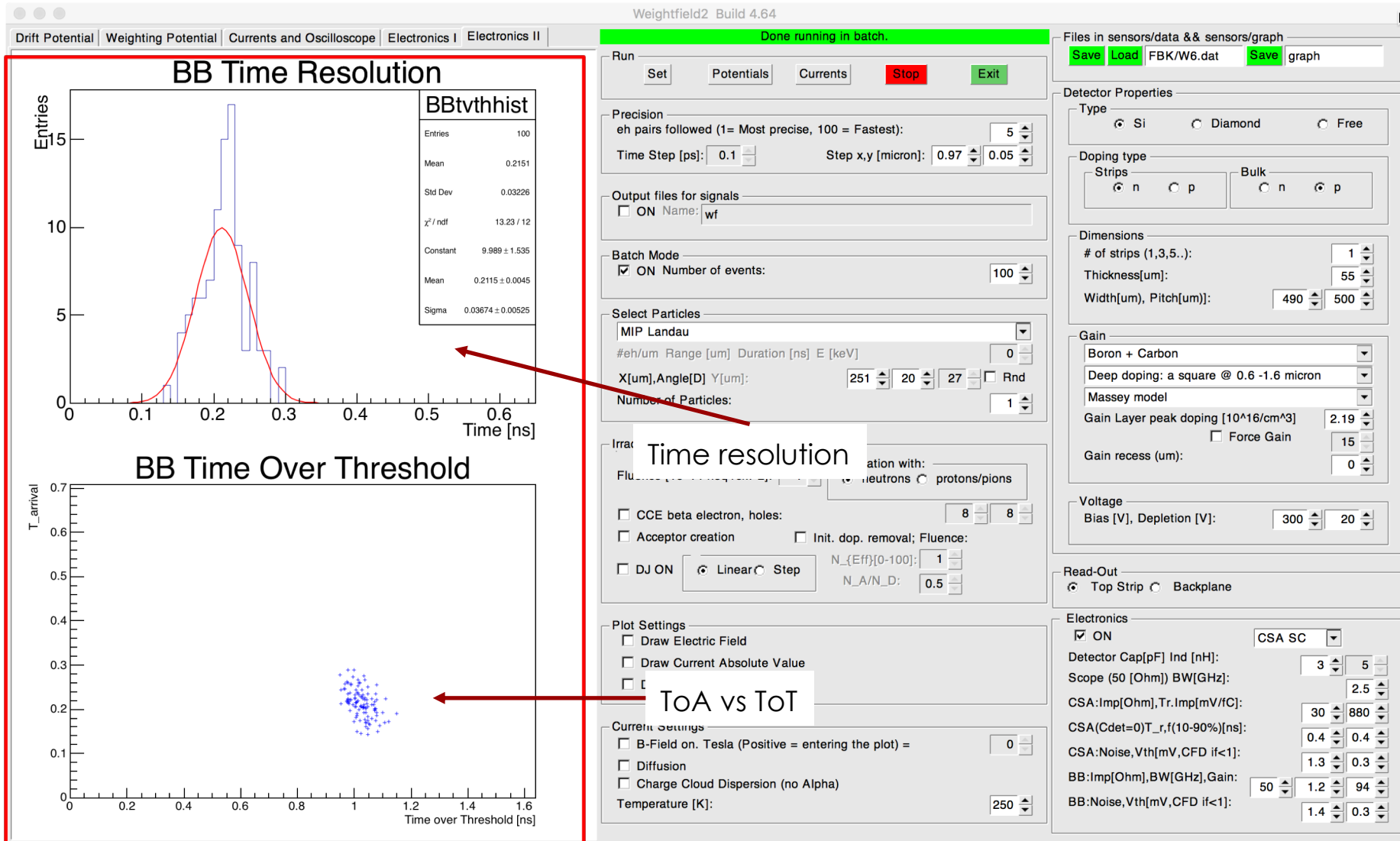


- ➔ Set the comparator threshold as low as you can
- ➔ Use thin sensors

# Batch mode: deposited & collected charges

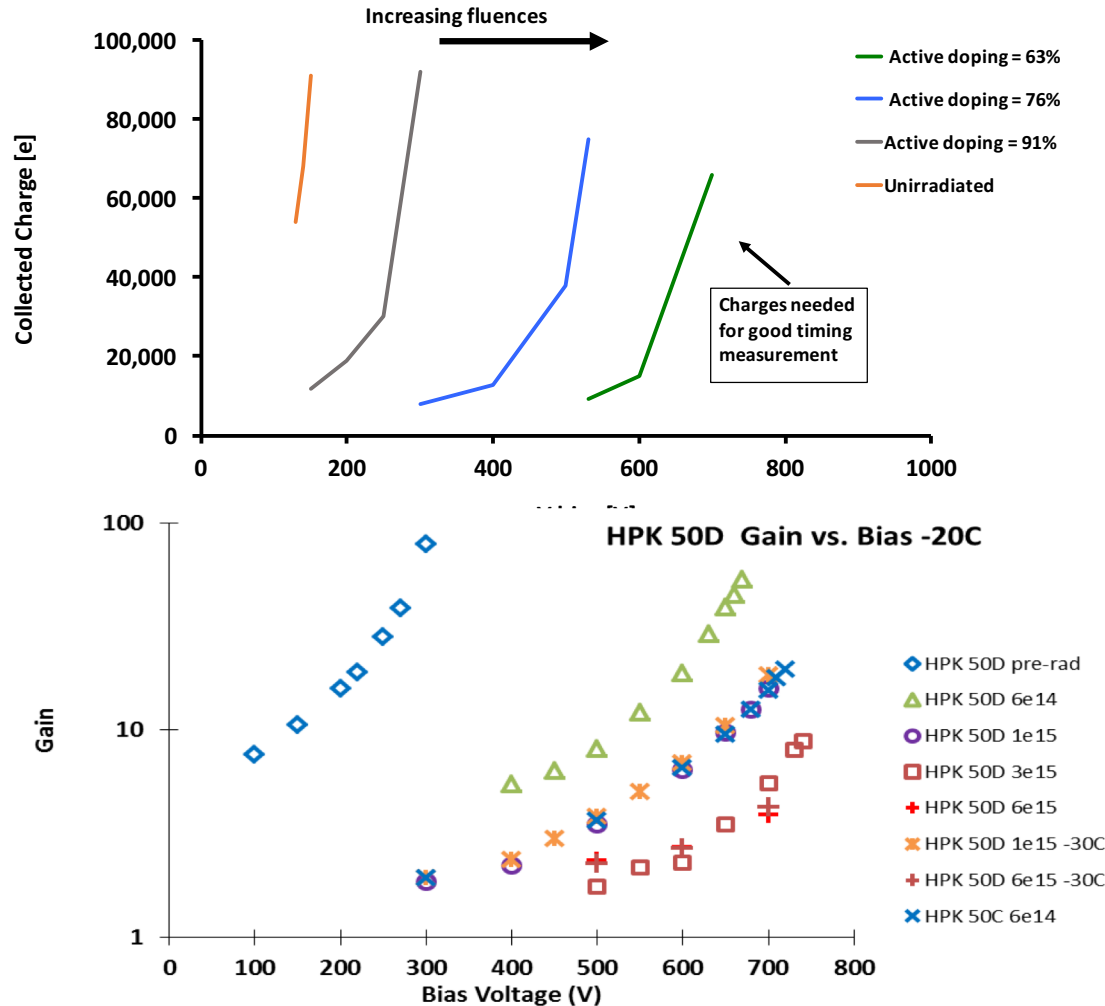


# Batch mode: time resolution



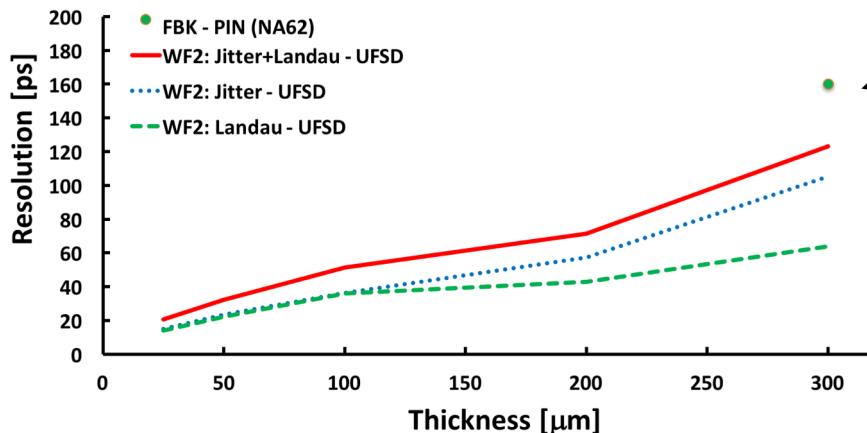
# Compensation with Vbias

The necessary field can be recovered by increasing the external Vbias:  
Vbias: proven to work up to  $5 \cdot 10^{15} \text{ n}^{\text{eq}}/\text{cm}^2$

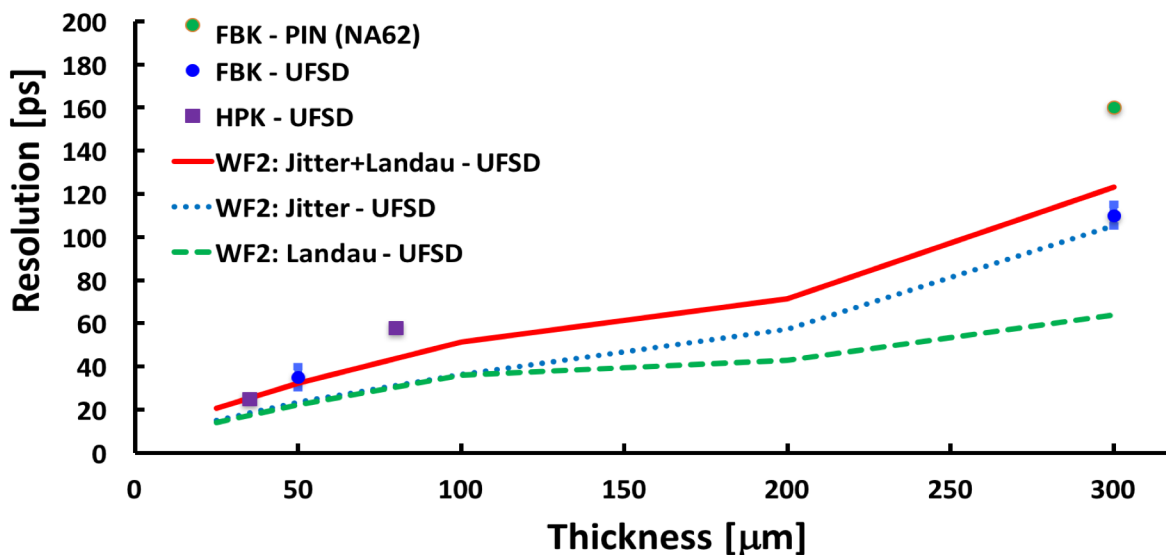


# Time resolution vs thickness

Comparison WF2 Simulation - Data  
Band bars show variation with temperature ( $T = -20^{\circ}\text{C} - 20^{\circ}\text{C}$ ), and gain ( $G = 20 - 30$ )

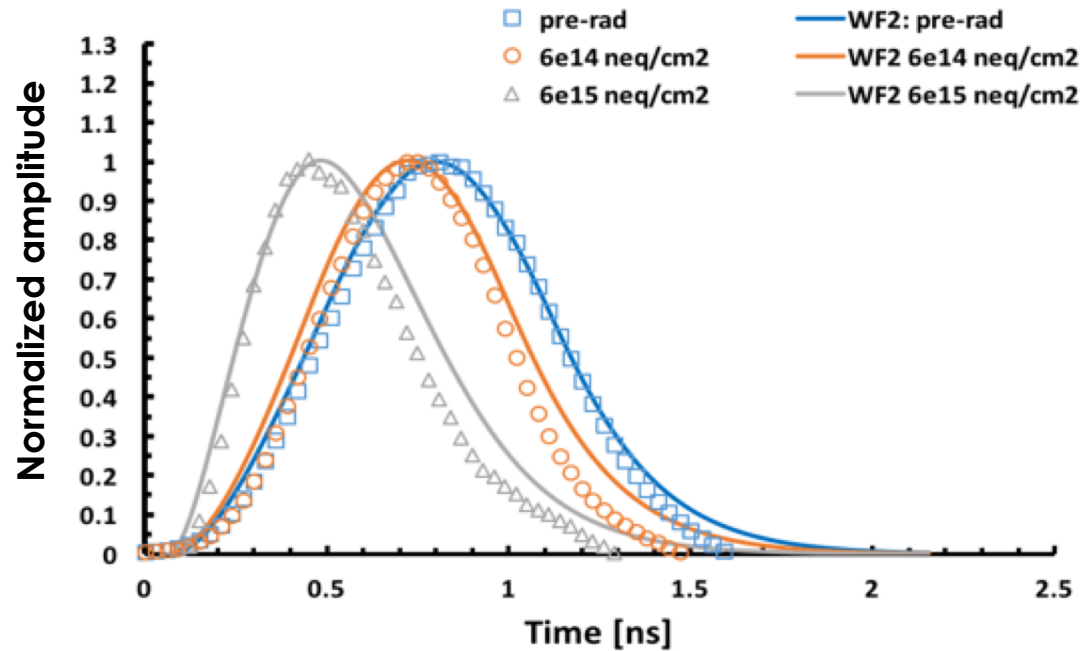


Comparison WF2 Simulation - Data  
Band bars show variation with temperature ( $T = -20^{\circ}\text{C} - 20^{\circ}\text{C}$ ), and gain ( $G = 20 - 30$ )



# Pulse shape in irradiated UFSD

Comparison measured - WF2 pulse of HPK 50D 50-micron thick sensors

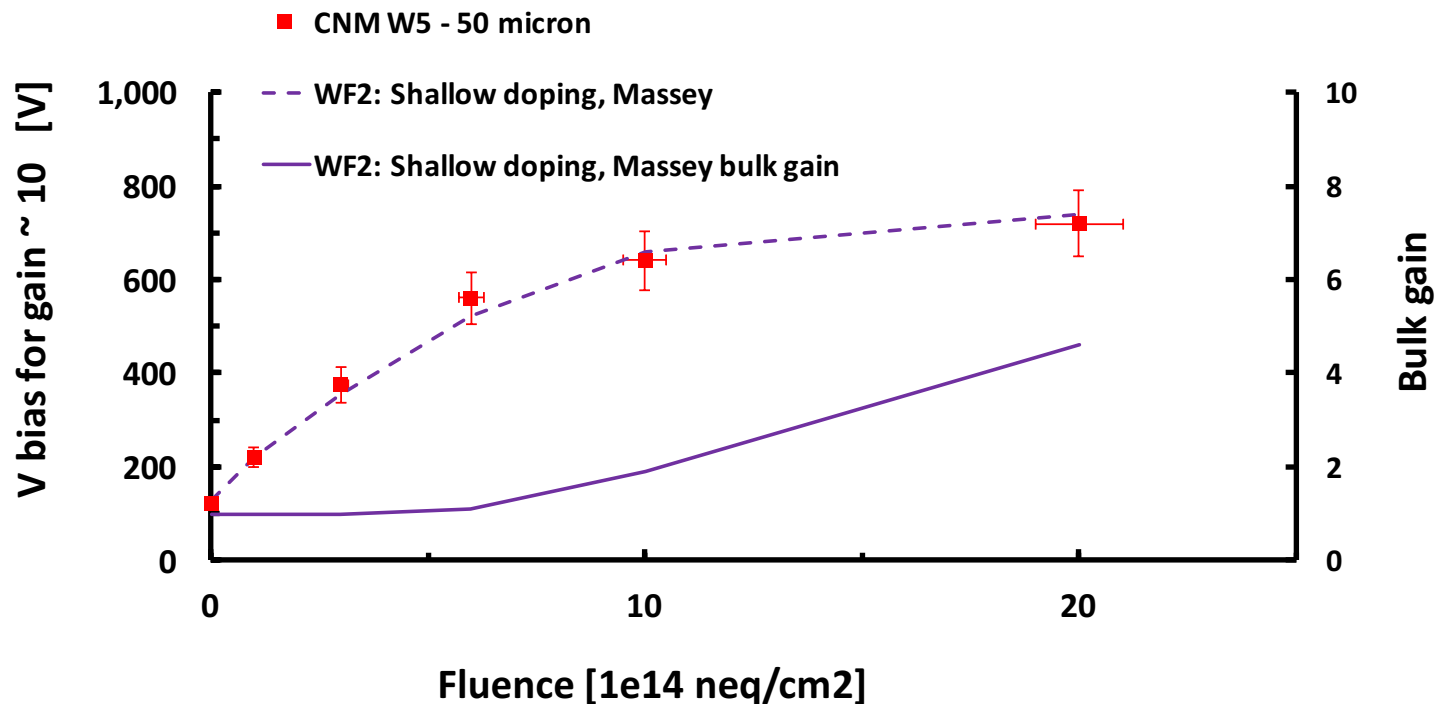


With irradiation the signal changes: it becomes shorter and steeper

# How to use UFSD up to $5 \sim 10^{15} n_{eq}/cm^2$

As the gain layer density decreases, we need to increase the external voltages to create the Efield needed for multiplications. In so doing, the gain moves from the gain layer to the bulk

**Bias voltage to obtain Gain  $\sim 10$  as a function of fluence**





# Conclusion

---

Weightfield2 is a rather easy to use simulator for silicon sensors

It can help the user's intuition in deciding the best solutions

It is fully configurable by the user

# Acknowledgement

---

This research was carried out with the contribution of the Ministero degli Affari Esteri, "Direzione Generale per la Promozione del Sistema Paese" of Italy.



*Ministero degli Affari Esteri  
e della Cooperazione Internazionale*

DIREZIONE GENERALE  
PER LA PROMOZIONE DEL SISTEMA PAESE  
*Unità per la cooperazione scientifica  
e tecnologica bilaterale e multilaterale*

The work is supported by HORIZON2020 Grants UFSD ERC grant UFSD669529